

FORM PTO-1449

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

(Use several sheets if necessary)

Docket Number (Optional)
81784.0291Application Number
Not Assigned [parent 09/291,538]

Applicant

Hidenori OGATA et al.

Filing Date

November 14, 2003

Group Art Unit

Not Assigned

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
My	5,432,122	07/1995	Chae			
	5,496,768	03/1996	Kudo			
	4,234,358	11/1980	Celler et al.			
	5,365,875	11/1994	Asai et al.			
	5,683,935	11/1997	Miyamoto et al.			
	5,529,951	06/1996	Noguchi et al.			
	5,591,668	06/1997	Maegawa et al.			
	4,514,895	05/1985	Nishimura			
	5,815,494	09/1998	Yamazaki et al.			
	5,767,003	06/1998	Noguchi			
	5,454,347	10/1995	Shibata et al.			
	5,533,040	07/1996	Zhang			
My	6,274,414	08/2001	Ogata et al.			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

My	M. Kamiya et al., "Excimer Laser Annealing SLA3600," pp. 24-25 with its English translations and Document 1 (Electronic Display Forum '96 program cover sheet, April 17-19, 1996) and Document 2 (List of presentations at Forum '96, including "Excimer Laser Annealing System SLA3600, April 19, No. 18) showing the laid open date of 4/17-4/19/1996
My	Mamoru Furuta et al., "Bottom-Gate Poly-Si Thin Film Transistors Using XeCl Excimer Laser Annealing and Ion Doping Techniques," IEEE Transactions on Electron Devices, vol. 40, No. 11, November, 1993

EXAMINER

Quarberg

DATE CONSIDERED

9/2004

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.